

Title (en)

METHOD FOR MAKING AN ELECTRON SOURCE WITH MICROTIPS

Title (de)

VEFAHREN ZUR HERSTELLUNG EINER MIKROSPITZEN-ELEKTRONENQUELLE

Title (fr)

PROCEDE DE FABRICATION D'UNE SOURCE D'ELECTRONS A MICROPOINTES

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Application

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Abstract (en)

[origin: FR2770683A1] The invention concerns a method which consists in making a structure comprising a substrate (10), at least one cathode conductor (12), a first insulating layer (14), a grid layer (16) and a second insulating layer (71). It consists in forming holes through the insulating layers and the grid layer, in forming a deposit (80) of a material emitting electrons in the holes up to the upper level thereof, treating this deposit to minimise or prevent a chemical etching from the top thereof, eliminating the second insulating layer and carrying out a chemical etching of the material to obtain the microtips. The invention is useful for making flat screens.

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